

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Kenichi SHIRAIISHI

Serial No. 10/589,437

Group Art Unit: 2851

Confirmation No. 9870

Filed: August 1, 2007

Examiner: Mesfin T. Asfaw

For: EXPOSURE APPARATUS, SUPPLY METHOD AND RECOVERY METHOD,
EXPOSURE METHOD, AND DEVICE PRODUCING METHOD

AMENDMENT

Mail Stop Amendment

Commissioner for Patents

PO Box 1450

Alexandria, VA 22313-1450

Sir:

This is in response to the Office Action mailed January 22, 2009, which has a period for response set to expire on April 22, 2009.

The following amendments and remarks are respectfully submitted. Reconsideration of the claims is respectfully requested.

Amendments to the claims begin at page 2; and

Remarks begin at page 9.